



Zong Zhan Wu 吳宗展

Semiconductor Engineer

Contact

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Skill

- Modules Maintenance
- Vacuum Systems
- Electrostatic Chuck
- Gas Panel
- Robot Teaching
- Plasma & RF troubleshooting
- Equipment Hook-up & Buy-offs
- Client Coordination

Education

- Dept. of Biomedical Engineering
National Cheng Kung University
2016.09 – 2019.03
- Dept. of Applied Mathematics
National Chiao Tung University
2012.09 – 2016.06

Certification

- English: TOEIC 740 (2023.06)
- Automatic control: 丙級工業配線 (2024.09)
- Water supply engineering: 丙級自來水配管(2024.11)

Summary

A semiconductor engineer with 5+ years of experience at leading organizations, including TSMC Fab 12B and Camtek. Proficient in core processes like Ion Implantation, ALD, and selective wet etching, alongside metrology tools such as AFM and 2D/3D AOI calibration. Managed the rapid deployment (move-in and hook-up) of 15 AOI tools, completing 3 buy-offs within six months. Skilled in AP8 project sponsorship, client coordination, and hardware troubleshooting to ensure operational excellence. Furthermore, I improved particle performance from 20 to 5 and increased tool availability by +5%. My comprehensive blend of hands-on technical mastery and strong project execution skills positions me to drive superior operational results in advanced manufacturing environments.

Experience

Customer Service Engineer 2025.03 – 2025.09 Camtek AOI Equipment

- Served as AP8 Installation Progress Sponsor, tracking materials, schedules, and coordinating with TSMC customers.
- Completed hook-up & move-in of 15 tools and buy-off of 3 tools within 6 months.
- Mastered 2D/3D measurement calibration in first 3 months and operated independently.
- Troubleshot robot controller connection issues, ensuring system stability and production accuracy.

Process Integration Engineer 2024.01 – 2025.03 Core Facility Center, National Cheng Kung University

- Specialized in surface modification and selective wet etching processes.
- Excelled in AFM surface roughness analysis and ALD deposition.
- Conducted research on silicon etching inhibitors and failure mode analysis of experimental outcomes.

Ion Implanter Equipment Engineer 2019.09 – 2022.09 TSMC, Fab 12B

- Managed ion implanter equipment for 3 years.
- Skill in high-pressure, ion plasma, vacuum, and pumping systems.
- Improved particle performance from 20 to 5 in germanium implant process, raising tool availability from 80% to 85%.
- Led rapid response and safety protocols during PH₃ gas leakage incidents.